Special Issue

Thin-Film Transistors: Materials, Fabrications and Applications

Message from the Guest Editor

Thin-film transistors (TFTs) have enabled a number of emerging applications, including flexible displays, biosensors, and back-end-of-line (BEOL)-compatible transistors towards monolithic 3D integration, in addition to more traditional applications such as liquid crystal display (LCD) and organic light-emitting diode (OLED) displays. These new applications have put great demands on TFT performance and fabrication. For instance, BEOL-compatible transistors require high-current drivability under a low-thermal-budget process. To fulfill the requirement of these emerging applications, innovations in channel and dielectric materials, device structures, and device fabrication processes are highly required. Accordingly, this Special Issue seeks to showcase research papers and review articles that focus on recent progress in materials, fabrications, and applications of thin-film transistors.

Guest Editor

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